

**Amendments to the Claims:**

Please amend the claims as follows:

Claim 1 (currently amended) An apparatus for loading and unloading wafers to and from the fabrication equipment, having a ~~especially an apparatus with an improved main assembly, said main assembly comprising:~~

a port plate;

a base;

~~two~~ first and second port plate supporters each having a top end and a bottom end, ~~with two lead screws and a lead device installed thereon~~, the top ends of said ~~two~~ port plate supporters being connected to ~~said~~ the port plate ~~and~~; the bottom ends of ~~said two port plate supporters~~ being connected to ~~said~~ the base;

a first lead screw and corresponding lead device installed on the first plate supporter;

a second lead screw and corresponding lead device installed on the second plate supporter;

a port door with two screw nuts installed at opposite sides thereof, ~~said~~ the port door being coupled ~~serewed~~ to ~~said~~ the first and second ~~two~~ lead screws via ~~said~~ the two screw nuts;

a lifting/lowering drive mechanism installed on ~~said~~ the base, ~~said lifting/lowering drive mechanism~~ comprising a motor, timing pulleys, and timing belts, wherein the ~~said~~ lifting/lowering drive mechanism ~~can~~ drives the first and second ~~said~~ lead screws to move ~~said~~ the port door upwards or downwards via ~~said~~ the timing pulleys and timing belts through the power generated by ~~said~~ the motor;

protective covers covering the first and second port plate supporters,  
repectively;

an intake filtering system having a filter installed in the base and a plurality of  
intake pipes installed at openings of the protective covers to form an air shield to  
prevent particles from going out and contaminating wafers; and

for each of the first and second lead screws, a spring grommet installed  
between a top end thereof and the port plate and a spring grommet installed between a  
bottom end thereof and the base for absorbing a pitch error between the screw nut and  
the corresponding lead screw.

Claim 2 (currently amended) The apparatus for loading and unloading wafers of claim 1, wherein the apparatus further comprises a pod hold-down latch mechanism module and a wafer reseal mechanism module ~~are~~ installed on ~~said~~ the port plate.

Claim 3 (canceled)

Claim 4 (currently amended) The apparatus for loading and unloading wafers of claim 1, wherein ~~said~~ each of the first and second port plate supporters are made of a U-shaped plates of with high rigidity.

Claim 5 (currently amended) The apparatus for loading and unloading wafers of claim 1, wherein the apparatus further comprises a pod unlock mechanism module is installed on ~~said~~ the port door.

Claim 6 (currently amended) The apparatus for loading and unloading wafers of claim 1, wherein ~~two opposite-sides of said~~ the port door are secured to ~~two~~ drive plates, each of said ~~two~~ drive plates having a screw nut thereon to be screwed to said lead screw via said screw nut, two shaft bearings being installed on one of said ~~two~~ drive plates, said

two shaft bearings being slidably matched on two lead poles to form said lead device.

Claim 7 (canceled)

Claim 8 (currently amended) The apparatus for loading and unloading wafers of claim 1, wherein ~~said~~ the base has a plurality of positioning holes disposed thereon to be fixed on the fabrication equipment.

Claim 9 (currently amended) The apparatus for loading and unloading wafers of claim 1, wherein ~~said~~ the lifting/lowering drive mechanism ~~also~~ further has idle wheels contacting the ~~sticking to said~~ timing pulleys.